

Jun. 15. 2004 2:58PM Haynes Beffel & Wolfeld LLP

No. 0756 P. 1

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 Paula Faulk Hurley

15 June 2004

ATTY DOCKET: MXIC 1555-1**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application Inventor(s): Shu-Sing Liao Appl. No.: 10/801,954 Confirm. No.: 2359 Filed: 16 March 2004 Title: Method and System for Analyzing Defects of an Integrated Circuit Wafer	Group Art Unit: 2812 Examiner: Unassigned <u>Customer No. 22470</u>
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Commissioner for Patents
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REQUEST FOR CORRECTED FILING RECEIPT

Sir:

Attached is a marked-up copy of the official Filing Receipt to identify the correction needed.

The correction is as follows:

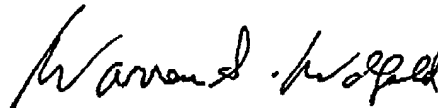
Please change the country of the first inventor from CHINA to **REPUBLIC OF CHINA**.

Please change the country of the second inventor from CHINA to **REPUBLIC OF CHINA**.

Please change the location of the Assignee from Hsinchu, CHINA to **Hsinchu, Taiwan, REPUBLIC OF CHINA**.

Since the error was not caused by applicant, but by the Patent Office, no fee is believed necessary. However, the Commissioner is hereby authorized to charge any additional fees that may be required by this paper, or to credit any overpayment to Deposit Account No. 50-0869 (MXIC 1555-1). This paper is submitted in duplicate.

Respectfully submitted,



Warren S. Wolfeld, Reg. No. 31,454

Dated: 15 June 2004

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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/801,954	03/16/2004	2812	1112	MXIC 1555-1	6	39	2

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CONFIRMATION NO. 2359

22470
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FILING RECEIPT:



OC000000012862503

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Applicant(s)

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Assignment For Published Patent Application

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Hsinchu, Taiwan,
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Domestic Priority data as claimed by applicant

Foreign Applications

If Required, Foreign Filing License Granted: 06/03/2004

Projected Publication Date: 09/22/2005

Non-Publication Request: No

HAYNES BEFFEL & WOLFELD LLP

Early Publication Request: No

JUN 07 2004
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Title

Method and system for analyzing defects of an integrated circuit wafer

Preliminary Class

438

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